

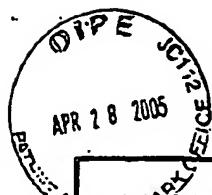
3/26/04

INFORMATION DISCLOSURE CITATION PTO-1449		ATTY. DOCKET NO. P132-US		SERIAL NO. 10/811449 Not Yet Assigned		
		APPLICANT Jim Dunphy, et al.				
		FILING DATE Herewith		GROUP Not Yet Assigned		
U.S. PATENT DOCUMENTS						
EXAMINER'S INITIALS	PATENT NO.	DATE	NAME	CLASS	SUBCLASS	FILING DATE
Dle	U.S Pub App No. 2003/0002019	1/2/03	Miller			
	U.S Pub App No. 2002/0056898	5/16/02	Lopes, et al.			
	U.S Pub App No. 2002/0063322	5/30/02	Robbins, et al.			
	6,300,294	10/9/01	Robbins, et al.			
	5,694,740	12/9/97	Martin, et al.			
	5,936,758	8/10/99	Fisher, et al.			
Dle	5,610,438	3/11/97	Wallace, et al.			
	5,512,374	4/30/96	Wallace, et al.			
FOREIGN PATENT DOCUMENTS						
EXAMINER'S INITIALS	PATENT NO.	DATE	COUNTRY	CLASS	SUBCLASS	TRANSLATION
						YES
						<input type="checkbox"/> <input checked="" type="checkbox"/>
OTHER DOCUMENTS (Including Author, Title, Date, Pertinent Pages, Etc.)						
Dle	"Lubrication of Digital Micromirror Devices" Henck, Tribology Letters 3 (1997) 239-247					
	Micromotor Operation in a Liquid Environment" Dhuler, IEEE 1992 pgs 10-13					
	"Optimization of Lubricants for silica Micromotors" Zarid, Sensors and Actuators A 46-47 (1995) 598-600					
	"Fabrication of packaged thin beam structures by an improved driving method" Masato Ohtsu, IEEE (1996) 0-7803-2985-6, pgs 228-233					
	"Operation of electrostatic micromotors in liquid environments" Mehran Mehregany, J. Micromech. Microeng. 2 (1992) 1-3					
	"Nanotribology and nanomechanics of MEMS devices", Nharad Bhushan, IEEE 0-7803-298-5-6, pgs 91-98					
	"Micromotor dynamics in lubricating fluids" Keren Deng, J. Micromech. Microeng. 4 (1994) 266-269					
	"Stiction reduction processes for surface micromachines" Roya Maboudian Tribology letters 3 (1997) 215-221					
	"Friction and Pull-off Force on Silicon Surface Modified by FIB" Ando IEEE 1996, 0-7803-2985-6/96, pgs 349-353					
	"Measurement of Micromotor Dynamics in Lubricating Fluids" Deng IEEE					
Dle	"Friction and Wear studies on Lubricants and materials Applicable to MEMS" Shigehisa Suzuki, IEEE 1991, pgs 143-147					
EXAMINER	Dle	DATE CONSIDERED		6/2/05		

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INFORMATION DISCLOSURE CITATION APR 28 2005 PTO-1449 SHEET 1 OF 2		ATTY. DOCKET NO.		SERIAL NO.		
		P132-US		10/811,449		
		APPLICANT Dunphy, et al.				
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U.S. PATENT DOCUMENTS						
EXAMINER'S INITIALS	PATENT NO.	DATE	NAME	CLASS	SUBCLASS	FILING DATE
Dh	5,939,785	8/17/99	Klonis, et al.			—
	5,411,769	8/17/99	Hornbeck			—
	6,204,085	3/20/01	Strumpell, et al.			—
	2003/0064149	4/3/03	Miller			—
	6,259,551	7/10/01	Jacobs			—
	5,447,600	9/5/95	Webb			—
	6,300,294	10/9/01	Robbins, et al.			duplicated
	6,086,726	7/11/00	Renk, et al.			—
	6,475,570	11/5/02	Jacobs			—
	2004/0100677	5/27/04	Huibers, et al.			—
Dh	2004/0125346	7/1/04	Huibers			—
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Dh	W. Robert Ashurst, et al., WAFER LEVEL ANTI-STICKTION COATINGS FOR MEMS., Sensors and Actuators A 104 (2003), Pgs 213-221.					
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	W. Robert Ashurst, et al., NANOMETER-THIN TITANIA FILMS WITH SAM-LEVEL STICKTION AND SUPERIOR WEAR RESISTANCE FOR RELIABLE MEMS PERFORMANCE, 4 pgs.					
	B.C. Bunker, et al., THE IMPACT OF SOLUTION AGGLOMERATION ON THE DEPOSITION OF SELF-ASSEMBLED MONOLAYERS, 2000 American Chemical Society, Pgs 7742-7751.					
	W. Robert Ashurst, et al., ALKENE BASED MONOLAYER FILMS AS ANTI-STICKTION COATINGS FOR POLYSILICON MEMS, Berkeley Sensor & Actuator Center, 4 pgs.					
	S Imad-Uddin Ahmed, et al., USING SELF ASSEMBLED MONOLAYERS TO REDUCE FRICTION AND WEAR IN POLYSILICON BASED MEMS, 2000, Pgs. 1-18.					
Dh	Uthara Srinivasan, et al., SELF ADDRESSED FLUOROCARBON FILMS FOR ENHANCED STICKTION REDUCTION, 1997 ieee, Pgs. 1399-1402.					
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Dle	2004/0012838	1/22/04	Huibers			
	2004/0100594	5/27/04	Huibers, et al.			
	2004/0156090	8/12/04	Patel, et al.			
	5,835,256	11/10/98	Huibers			
	6,046,840	4/4/00	Huibers			
	6,844,959	1/18/05	Huibers, et al.			
Dle	6,867,897	3/15/05	Patel, et al.			
Dle	5,287,096	2/15/94	Thompson, et al.			

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	"Fabrication of packaged thin beam structures by an improved driving method" Masato Ohtsu, IEEE (1996) 0-7803-2985-6, pgs 228-233					
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	6,204,085	3/20/01	Strumpell, et al.	-----	-----	-----
	2003/0064149	4/3/03	Miller	-----	-----	-----
	6,259,551	7/10/01	Jacobs	-----	-----	-----
	5,447,600	9/5/95	Webb	-----	-----	-----
	6,300,294	10/9/01	Robbins, et al.	-----	-----	-----
	6,086,726	7/11/00	Renk, et al.	-----	-----	-----
	6,475,570	11/5/02	Jacobs	-----	-----	-----
	2004/0100677	5/27/04	Huibers, et al.	-----	-----	-----
Dle	2004/0125346	7/1/04	Huibers	-----	-----	-----

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	2004/0100594	5/27/04	Huibers, et al.	██████	██████	██████
	2004/0156090	8/12/04	Patel, et al.	██████	██████	██████
	5,835,256	11/10/98	Huibers	██████	██████	██████
	6,046,840	4/4/00	Huibers	██████	██████	██████
	6,844,959	1/18/05	Huibers, et al.	██████	██████	██████
Dle	6,867,897	3/15/05	Patel, et al.	██████	██████	██████
Dle	5,287,096	2/15/94	Thompson, et al.	██████	██████	██████

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